

1. Properties of Optical Systems
 - 1.1. Optical Properties of a Single Spherical Surface (Brief Review)
 - 1.1.1. Refractive Surface: Radius, Curvature, Focal Length and Power
 - 1.1.2. Reflective Surface: Focal Length and Power
 - 1.1.3. Gaussian Imaging Equation
 - 1.1.4. Newton's Equation
 - 1.2. Aperture and Field Stops (Brief Review)
 - 1.2.1. Aperture Stop Definition
 - 1.2.2. Marginal Ray
 - 1.2.3. Chief Ray
 - 1.2.4. Vignetting
 - 1.2.5. Field Stop Definition
 - 1.2.5.1. Image Sensor as Field Stop
 - 1.2.5.1.1. Standard CCD/CMOS sensor dimensions
 - 1.3. First Order Properties of an Optical System (Brief Review)
 - 1.3.1. Gaussian Reduction (Conceptually)
 - 1.3.2. ynu raytrace
 - 1.3.3. Cardinal Points
 - 1.3.4. Entrance and Exit Pupils
 - 1.3.5. Extension of Gaussian Imaging to Thick Systems
 - 1.3.6. Transverse and Longitudinal Magnification
 - 1.3.7. Lagrange invariant, Etendue, Throughput, $A\Omega$ Product
 - 1.3.8. F-Number, Working F-Number and Numerical Aperture
 - 1.3.9. Depth of Field
 - 1.3.10. Field of View
 - 1.3.11. Front and Back Focal Distances
 - 1.3.11.1. Standard Flange distances for cameras
 - 1.4. Measurement of First Order Properties of Optical Systems
 - 1.4.1. Measurements based on Gaussian Imaging Equation
 - 1.4.2. Autocollimation Technique
 - 1.4.3. Neutralization Test
 - 1.4.4. Focimeter
 - 1.4.5. Focal Collimator
 - 1.4.6. Reciprocal Magnification
 - 1.4.7. Nodal-Slide Lens Bench
 - 1.5. Diffraction and Aberrations
 - 1.5.1. Black Box Optical System based on Cardinal Points and Pupils.
 - 1.5.2. Wavefront Picture of Optical Imaging
 - 1.5.3. Diffraction-Limited Systems and Connection to Fresnel Diffraction
 - 1.5.4. Point Spread Function (PSF) calculation and dimensions
 - 1.5.5. Sign and Coordinate System Conventions
 - 1.5.6. Optical Path Length (OPL), Optical Path Difference (OPD), Wavefront Error
 - 1.5.7. Transverse Ray Error and Spot Diagrams
 - 1.5.8. Aberrations of Rotationally Symmetric Optical Systems
 - 1.5.8.1. Piston and Tilt
 - 1.5.8.2. Seidel Aberrations

- 1.5.9. Aberrations of General Optical Systems
 - 1.5.9.1. Examples of non-rotationally symmetric systems
 - 1.5.9.2. Generalization of Seidel Aberrations to on-axis case
 - 1.5.9.3. Zernike polynomials
 - 1.5.9.3.1. Different variations found in literature
 - 1.5.9.3.2. Normalization, Radial Polynomials, Azimuthal components
 - 1.5.9.3.3. Examples of different orders of Zernike polynomials
 - 1.5.9.3.4. Representation of complex wavefront as linear combination
 - 1.5.9.3.5. Coordinate system conversions
 - 1.5.9.3.6. Pupil Size Conversion
 - 1.5.9.3.7. Fitting wavefront error to Zernike polynomials
- 1.5.10. Through-Focus PSF and Star Test
 - 1.5.10.1. Diffraction Limited Case (Defocus)
 - 1.5.10.2. Seidel Spherical Aberration
 - 1.5.10.3. Zernike Spherical Aberration
 - 1.5.10.4. Astigmatism
 - 1.5.10.5. Coma
- 1.5.11. Measurement of Distortion
 - 1.5.11.1. Conventional case
 - 1.5.11.2. Special Cases anamorphic, $f\theta$ lens. Scheimpflug
- 1.6. Optical Quality Metrics
 - 1.6.1. Resolution Targets
 - 1.6.1.1. Rayleigh Criterion
 - 1.6.2. Strehl Ratio
 - 1.6.3. Peak-to-Valley and rms Wavefront Error
 - 1.6.3.1. Relationship to Zernike Coefficients
 - 1.6.3.2. Relationship to Strehl Ratio
 - 1.6.4. Encircled and Ensquared Energy
 - 1.6.5. Optical Transfer Function (OTF)
 - 1.6.5.1. Modulation Transfer Function (MTF)
 - 1.6.5.2. Phase Transfer Function (PTF)
 - 1.6.5.3. Fourier Transform relationship to PSF
 - 1.6.5.4. Autocorrelation of Pupil Function
 - 1.6.5.5. Line Spread Function
 - 1.6.5.6. Siemens Star
- 1.7. Aspheric Surfaces
 - 1.7.1. Conics
 - 1.7.2. Quadrics
 - 1.7.3. Higher Order Aspheres
 - 1.7.3.1 Forbes Q Polynomials
 - 1.7.4. Torics
 - 1.7.5. Cylinders
- 2. Fabrication of Optical Surfaces
 - 2.1. Optical Materials
 - 2.1.1. Glass and Plastics
 - 2.1.2. Cauchy and Sellmeier Equations

- 2.1.3. Infrared and Ultraviolet Materials
- 2.2. Grinding and Polishing Flats, Windows and Prisms
- 2.3. Grinding and Polishing Spherical Surfaces
- 2.4. Grinding and Polishing Aspheric Surfaces
- 2.5. Diamond Turning and Fast Tool Servo
- 2.6. Magnetorheological Finishing
- 3. Non-interferometric Testing
 - 3.1. Autocollimator Tests
 - 3.2. Surface Radius of Curvature
 - 3.2.1. Geneva Gauge
 - 3.2.2. Spherometer
 - 3.2.3. Autostigmatic measurements
 - 3.3. Wavefronts
 - 3.3.1. Foucault Knife Edge Test
 - 3.3.2. Wire Test
 - 3.3.3. Ronchi Test
 - 3.3.4. Hartmann Screen Test
 - 3.3.5. Shack-Hartmann Sensor
 - 3.3.5.1. Fitting Shack-Hartmann Data to Zernike polynomials
- 4. Basic Interferometry and Optical Testing
 - 4.1. Review of Two Beam Interference
 - 4.1.1. Plane waves
 - 4.1.2. Spherical waves
 - 4.1.3. General wavefront shapes
 - 4.1.4. Visibility
 - 4.1.5. Coherence and Polarization
 - 4.2. Newton's Rings
 - 4.2.1. Patterns
 - 4.2.2. Determining convexity
 - 4.2.3. Test Plates
 - 4.3. Fizeau Interferometer
 - 4.3.1. Classical Fizeau
 - 4.3.2. Configurations for Flats, Concave and Convex Surfaces
 - 4.3.3. Laser Fizeau
 - 4.4. Twyman-Green Interferometer
 - 4.4.1. Common Configurations
 - 4.5. Mach-Zehnder Interferometer
 - 4.5.1. Common Configurations
 - 4.5.2. Single Pass
 - 4.6. Lateral Shearing Interferometers
 - 4.6.1. Common Configurations
 - 4.6.2. Derivatives of wavefronts
 - 4.7. Interferograms
 - 4.7.1. Seidel Aberrations
 - 4.8. Phase-Shifting Interferometry
 - 4.8.1. Phase Shifters

- 4.8.2. Algorithms
- 4.8.3. Phase unwrapping
- 4.8.4. Calibration and errors
- 4.9. Testing Aspheric Surfaces
 - 4.9.1. Computer Generated Holograms
- 5. Optical Specification
 - 5.1. ISO 1101 Standard
 - 5.2. ISO 10110 Standard
 - 5.2.1. General
 - 5.2.2. Stress Birefringence
 - 5.2.3. Bubbles and Inclusions
 - 5.2.4. Homogeneity
 - 5.2.5. Surface Form Errors
 - 5.2.6. Centering
 - 5.2.7. Surface Imperfections
 - 5.2.8. Texture
 - 5.2.9. Surface Treatment and Coatings
 - 5.2.10. Tables for Elements and Assemblies
 - 5.2.11. Non-toleranced Data
 - 5.2.12. Aspheric Surfaces
 - 5.2.13. Wavefront Deformation
 - 5.2.14. Laser Damage Threshold